

ABSTRACT OF THE DISCLOSURE

A piezoelectric/electrostrictive film type device includes a substrate formed of a ceramic and a piezoelectric/electrostrictive operation portion in which at least one piezoelectric/electrostrictive layer and at least one pair of electrodes electrically connected to the piezoelectric/electrostrictive layer are stacked on the substrate. In the device, an outer surface of the piezoelectric/electrostrictive layer is subjected to surface modification to obtain a highly water repellent surface for inhibiting infiltration of moisture into micro-pores opened in the outer surface or into a gap between the substrate and the piezoelectric/electrostrictive layer. The piezoelectric/electrostrictive film type device has flexural displacement and durability equal to or more than those of a conventional piezoelectric/electrostrictive film type device and has a relatively high resonance frequency and is superior in high-speed response.